Optical Properties of MoSe₂ Monolayer Implanted with Ultra-Low-Energy Cr Ions

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1. INTRODUCTION

The properties of semiconductors, especially atomically thin monolayer (ML) semiconductors, depend strongly on the types and densities of defects in their crystal lattices. The most technologically relevant defects are dopants, i.e., foreign atoms in substitutitional positions in the crystal lattice. Shallow dopants introduce free electrons or holes into the conduction or valence band and thus change the semiconductor conductivity. As such, they facilitate the fabrication of p–n junctions, which underpins most active optoelectronic devices.

Doping with transition-metal atoms has been shown to introduce ferromagnetic order in p-doped semiconductors. Impurity atoms can also trap electrons or holes or bind excitons. Radiative recombination involving such states can be detected as sub-band-gap photoluminescence (PL). Single foreign atom that bind excitons have been explored for single photon sources. Alternatively, if the dopant atom has a functionality of a spin qubit, the bound excitons provide an optical readout of its state. The binding of excitons to the dopant atoms depends not only on electron and hole masses but also on the dielectric constant of the semiconductors. Because of that, excitonic effects in bulk semiconductors are only observed at cryogenic temperatures. Foreign atoms can also act as color centers in semiconductors and insulators. Spin qubits based on the color centers have been realized in diamond or SiC.

In two-dimensional (2D) semiconducting transition-metal dichalcogenides (TMDs), which feature weak electrostatic screening, substitutional atoms tend to introduce deep levels in the band gaps. While excitons have considerable binding energies, they are predicted to be very weakly bound to individual doping atoms. Optical transitions involving defect states have been observed, with defects identified as vacancies. The transition responsible for the PL was found to occur between the hybridized defect states and 2D lattice electronic states.

Among several methods of doping bulk semiconductors, ion implantation offers the highest flexibility in choosing implanted elements. Ion energies of tens of keV are used for implantation since functional layers can be even a hundred nanometers below the surface. High-energy ion implantation has been used...
to modify 2D materials, but its efficiency is low in this case, as most atoms go through the 2D target. Moreover, the ions penetrating through the ML can cause undesirable effects, e.g., trapped charges in the substrate. Implantation into 2D materials has the highest implantation efficiency with ion energies in the range of tens of eV. At these energies, the implantation efficiency and threshold energy depend on the ions’ mass and also chemical properties. Ultra-low-energy ion implantation has recently been demonstrated to be efficient in doping graphene using 40 eV Mn ions or Se ion implantation into MoS₂ with an energy of 20 eV. The ratio of the replaced S atoms with Se in the top sublattice was sufficient to form a Janus compound MoS₂−xSeₓ, as indicated by Raman spectroscopy and the transmission electron microscopy imaging.

Here, we study the optical properties of molybdenum diselenide (MoSe₂) ML implanted with 25 eV ⁵²Cr⁺ ions. Sub-band-gap defect-induced PL emission was observed only at the low n-doping level and with saturation behavior, characteristic of defects with low density. Ab initio molecular dynamics (MD) simulations of the implantation process were performed, and possible configurations of the Cr atoms in the MoSe₂ ML lattice were outlined to understand the atomic structure of the implanted MLs. The optical properties of the MoSe₂ ML with such defects were calculated using density functional theory (DFT). The most probable defect configurations were identified by combining experimental data and theoretical calculations.

2. RESULTS

2.1. Sample Preparation and Ion Implantation. A sample for ion implantation was prepared by mechanical exfoliation of the MoSe₂ graphite (Gr), and hexagonal boron nitride (hBN) flakes and their sequential transfer onto the Si/SiO₂ substrate with pre-patterned Ti/Au contacts. The use of the dry viscoelastic transfer technique ensured that the surface of the ML was sufficiently clean for the implantation. The MoSe₂ ML has to be grounded during the implantation. An electric contact to the ML was provided by placing the multilayer part of the exfoliated MoSe₂ flake on a Ti/Au metal contact. The ML was placed atop a graphite gate connected to another Ti/Au contact. The ML was separated from the gate with an hBN flake. Once completed, the device was implanted with ⁵²Cr⁺ ions at 25 eV and a fluence of 3 × 10¹³ cm⁻² (equivalent to 0.003 Cr per ML MoSe₂ unit cell, using the MoSe₂ ML in-plane lattice constant 3.32 Å²). The implantation was performed with the device heated to 220 °C. Following the implantation and initial characterization, another hBN flake was deposited on the ML MoSe₂ for full encapsulation, which protects the ML from interactions with the environment during the optical measurement and reduces the inhomogeneous broadening in the PL linewidth. The device was annealed at 150 °C to improve the interface between the constituent layers. The complete device is shown in Figure 1. More details are available in Section 5.

2.2. Optical Spectroscopy Data. Figure 2a shows PL spectra of weakly electron-doped pristine and Cr-implanted MoSe₂ MLs, measured at 10 K with the same laser power of 1 μW. Both spectra show similar features around the band-gap transitions, with an emission line from neutral excitons (X) and negative trions (X⁻). The red shift of these transitions in the Cr-implanted sample (Figure 2a) is most likely due to a difference in the dielectric environment or strain between the samples. The level of implantation is too low to expect changes in the band gap. Significant homogeneous broadening of the X line was determined by the Voigt function fitting. It resulted in the Lorentzian width of nearly 7 meV for the implanted sample, compared to about 2 meV for the pristine sample, suggesting a much shorter lifetime of the former. The most significant difference between the samples is a broad emission at around 1.51 eV, which we label D.

The relative intensity of the D peak compared to X⁻ and X continues to grow linearly. The saturating behavior of the D intensity, shown in Figure 2c, can be expressed phenomenologically as

\[ I \propto \frac{P}{P + P_{sat}} \quad \text{(1)} \]

with saturation power \( P_{sat} \approx 10 \mu W \). The saturating behavior is expected when the exciton generation rate exceeds the recombination rate of the states responsible for D. The saturation threshold depends on the density of states and the lifetime of the recombining carriers. The low threshold for D is consistent with the low implantation level. The lifetime of carriers was measured from time-resolved PL. The decay of the population of the excited states contributing to the D peak after a pulsed excitation can be seen in Figure 2d. As can be expected from measuring an ensemble of emitters, the decay is
not a single exponential. The very fast initial decay of population by about 10%, which is faster than the time resolution of the experiment, is followed by a slower decay with the 1/$e$ decay time of around 14 ns. These decay times are 2−3 orders of magnitude longer than the lifetime of free excitons in MoSe$_2$ MLs$^{30,31}$ and one order of magnitude longer than that from the isolated, confined excitons,$^{32}$ pointing to a low oscillator strength of the emitters. The doping-dependent PL from neutral and charged excitons shown in Figure 3a is typical of MoSe$_2$ MLs. When increasing the gate voltage, the D emission only emerges after the signal from the positive trion, X$^+$, entirely disappears. It reaches the maximum intensity around 1 V; the gate voltage of the transition between X and X$^-$ dominated spectra. The blueshift of the D emission at higher gate voltage is likely to be due to the energy renormalization due to the screening by the free charges in the ML. Similar behavior for defect peaks was observed by others.$^{33}$ The D line weakens strongly as the X$^-$ line intensifies with a further gate voltage increase. This behavior suggests a competition between the exciton capture at the defect state and the formation of an X$^-$. This scenario is supported by the PL excitation (PLE) spectroscopy measurement (Figure 3b), which shows that the intensity of the D emission is maximum when the excitation wavelength is resonant with the energy of X around 1.637 eV. The D emission was not excited with laser resonant with X$^-$ (around 1.608 eV) even though the PL spectrum, measured at the same

Figure 2. PL of Cr-implanted MoSe$_2$ ML at 10 K. (a) PL spectra of Cr-implanted MoSe$_2$ ML (red curve) at low n-doping ($V_g = 0.8$ V), plotted with that of pristine MoSe$_2$ ML (black). In addition to the X$^-$ and X from MoSe$_2$ ML, the Cr-implanted sample also shows the broad D peak at around 1.51 eV. (b) PL spectra of Cr-implanted ML under laser power ranging from 36 nW to 123 μW. Spectra are normalized to X$^-$. Here, the sample is slightly n-doped at $V_g = 0.8$ V. (c) Power dependence of PL. Best-fit lines (dashed), with their standard deviations (shaded region around the lines), are plotted together with the extracted intensity from PL spectra (dots). Unless explicitly shown, the error bars are smaller than the size of the data points. X$^-$ and X are fitted with power law $I \propto P^\alpha$, and D is fitted with the saturation curve described by eq 1. (d) Time-resolved PL of Cr-implanted MoSe$_2$. 1/$e$ time is around 14 ns.
doping level, clearly shows that the ML is doped with electrons (X$^-$ emission is the strongest PL signal). Figure 4a compares gate-dependent PL at 22 and 108 K. While X$^-$ emission is the most intense line in the spectra at the lower temperature, it is very weak at the higher temperature. X becomes the strongest line, but D diminished less than X$^-$ and remains up to room temperature (Supporting Figure S4b). We trace the change of the PL signal counts from X$^-$ and D, both normalized to X signal counts, on the Arrhenius plot shown in Figure 4b. X$^-$ dissociates into higher-energy X and an electron at a higher temperature. Its intensity can be fitted with the standard Arrhenius formula

$$I(T) = \frac{I(0)}{1 + A \exp \left( \frac{-E_a}{k_B T} \right)}$$

(2)

where $I(0)$ is the PL intensity at temperature 0 K, A is a proportionality constant, $E_a$ is the activation energy for the dissociation of X$^-$, and $k_B$ is the Boltzmann constant. Fitting the formula to the data gives $E_a \approx 32 \pm 8$ meV, which is expected for a binding energy of the trion. The D emission intensity first increased with temperature up to around 34 K before diminishing. To account for this initial increase in intensity, we assume that the trapping of carriers that recombine requires overcoming the activation energy. We use a modified multilevel model for the temperature dependence of the D intensity

$$I(T) = \frac{I(0)}{1 + A_1 \exp \left( \frac{-E_{a1}}{k_B T} \right) + A_2 \exp \left( \frac{-E_{a2}}{k_B T} \right)}$$

(3)

where $A_1$ and $A_2$ are the proportionality constants, and $E_{a1}$ and $E_{a2}$ are the activation energies for trapping and detrapping of carriers, respectively. Fitting of the D peak yields $E_{a1} \approx 1.2 \pm 0.8$ meV and $E_{a2} \approx 30 \pm 7$ meV.

Temperature affects not only the intensity but also the D emission energy. The temperature-dependent energy shift of X and D lines can be described by the modified Varshni relation

$$E_{\text{shift}}(T) = E_0 - \frac{\alpha T^2}{T^2 + \beta}$$

(4)

where $E_0$ is the energy at $T = 0$, $\alpha$ and $\beta$ are constants. The energy shifts of X and D lines are then $E_X(T) = E_0 - \frac{\alpha_{X} T^2}{T^2 + \beta}$ and $E_D(T) = E_0 - \frac{\alpha_{D} T^2}{T^2 + \beta}$, respectively.

Figure 3. Doping level and excitation energy dependencies of PL. (a) Gate-dependent PL, where the backgate voltage $V_g$ was varied from $-12$ to $8$ V to tune the doping level in the ML from p- via neutral to n-doping. The carrier concentration $n$ is calculated using the simple parallel plate capacitor model (more details in the Supporting Note 7). (b) PLE of the D peak, taken at $V_g = 0.7$ V. The D peak intensity was integrated around its PL emission energy between 1.48 and 1.52 eV. Inset: PL spectrum under a 688 nm (1.80 eV) excitation under the gate voltage as applied for the PLE measurements.

Figure 4. Temperature dependence of PL emission. (a) Gate voltage-dependent PL at 22 and 108 K. (b) Arrhenius plot of X$^-$ and D (symbols). At each temperature, the two peaks’ integrated intensities were acquired at the doping levels, where each emission is the brightest. The intensities were then normalized to that of X (at the voltage where X is most intense). The best fit lines were according to eqs 2 and 3. (c) The temperature-dependent band gap of X and D (symbols). The best-fit line was according to eq 4.
Figure 5. Magneto-PL measurement of Cr-implanted MoSe$_2$ ML at 1.8 K. PL spectra acquired with out-of-plane magnetic field $B$ (varying between $-8$ and $8$ T) applied to the sample and excited with an H-polarized laser. The detection is set to measure either $\sigma^+$ (black) or $\sigma^-$ (red) polarization states. The figure shows the polarization-resolved PL spectra of (a) X and X$_-$, (c) D, with their Zeeman splitting $\Delta E_Z$ shown in (b, d). The splitting was calculated from the peak positions (extracted from fitting Voigt functions to the PL spectra), with the error bars representing the propagated standard deviation of the fit procedure. The Zeeman splitting of the three emissions reveals expected g-factors around $-4$ for X and X$_-$, only around $-1.18$ for D.

\[
E_b(T) = E_b(0) - S\langle \hbar \omega \rangle \left[ \coth \frac{\langle \hbar \omega \rangle}{2k_B T} - 1 \right]
\]

where $E_b(0)$ is the emission energy at 0 K, $S$ is the electron–phonon coupling, and $\langle \hbar \omega \rangle$ is the average phonon energy. Fitting gives $\langle \hbar \omega \rangle = 11.1 \pm 1.3$ meV and $S = 1.82 \pm 0.14$ for X, similar to the reported values ($\langle \hbar \omega \rangle \approx 12-20$ meV, $S \approx 2.37-30$). For the D emission, the fitted $\langle \hbar \omega \rangle$ and $S$ are 10.7 $\pm$ 1.5 and 0.79 $\pm$ 0.09 meV, respectively. A smaller $S$ constant compared to excitonic lines has been reported for vacancy-induced PL emissions from TMD MLs$^{33,34,40}$ and explained as a result of the defect being decoupled from the conduction band, which varies with the temperature. A similar scenario is also likely to be the case in our sample.

To gain further insight, we measured the PL emission from the sample under the out-of-plane magnetic field $B$ varying from $-8$ to $8$ T. Figure 5a shows the splitting of X and X$_-$ spectra in two circular polarization detection states under the applied B-field. The valley splitting, caused by the Zeeman effect$^{31,42}$ and defined as

$$\Delta E_Z = E_{\sigma^+} - E_{\sigma^-} = g\mu_B B$$

(where $E_{\sigma^+}$ and $E_{\sigma^-}$ are the emission energy in the detected circular polarization basis $\sigma^+$ and $\sigma^-$, respectively, $g$ is the Landé g-factor, $\mu_B$ is the Bohr magneton) changes linearly with the applied magnetic field (Figure 5b). The g-factors derived from the data are $-3.69 \pm 0.04$ and $-4.80 \pm 0.03$ for X and X$_-$, respectively. The g-factor value for X is close to the ones from the previous experimental work$^{28,41-45}$ which are between $-3.8$ and $-4.3$ and well within the expected range from $-3.22$ to $-3.82$ predicted by recent ab initio calculations.$^{46,47}$ The g-factor for X$_-$ is slightly higher than for X but similar to the values observed for samples under higher doping levels.$^{43-45}$ On the other hand, the D emission shows little change with the magnetic field (Figure 5c).

Comparing the energy of photons from the D peak in both circular polarization gives a g-factor of about $-1.18 \pm 0.06$. The peak position was determined by fitting the data with three Voigt functions and then taking the maximum of the fitted line. The uncertainty here is high, partly owing to the D peak’s large width.

2.3. First-Principles Molecular Dynamics Simulation of Cr-Ion Implantation into MoSe$_2$ ML. To get insights into the defect formation process and types of defects that can appear upon impacts of energetic Cr ions, we carried out DFT MD simulations, as described below. The atomic structure of a free-standing MoSe$_2$: rectangular slab containing 90 atoms was fully optimized; then, a Cr atom was placed 6 Å above its surface (Figure 6a) and a kinetic energy of 25 eV was assigned to the atom. Normal incidence was simulated; that is, the initial velocity vector of the projectile was oriented perpendicular to the surface of the ML. The projectile was assumed to be a neutral atom, as at such low energies and low...
charge states, its neutralization must occur well before it reaches the surface. We note that DFT MD on the Born–Oppenheimer surface cannot describe the evolution of charge transfer anyway, and the Ehrenfest dynamics should be used. 21 impact points were selected in the irreducible area of the primitive cell of MoSe$_2$ (Figure 6b), and the outcomes of the simulations were averaged with the corresponding weights. The MD runs continued until the kinetic energy brought up by the projectile was distributed over the whole supercell (normally after a few picoseconds); then, the system’s temperature was quenched to zero, and the atomic structure was analyzed. Although the effects of substrate on defect generation in a 2D system can be significant for ions with much higher (keV range) energies, the role of the substrate should be minimal for impacts of 25 eV Cr ions onto MoSe$_2$, so that a free-standing slab was simulated. Spin-polarized calculations were carried out. Although computationally more efficient non-spin-polarized method with a correction for isolated atom polarization energies can be used to simulate irradiation effects, the account for spin effects is particularly important for Cr, as it is magnetic, which affects the energetics of defect configurations.

Figure 6c shows the most common atomic configurations that appear after Cr atom impacts. These are Cr adatoms, X-sub configuration (Cr at Se sites with a Se adatom), interstitials (the Cr atom between Mo atoms), and substitutional defects in Mo and Se sites, which are Cr@Mo and Cr@Se, respectively. Table 1 lists the probabilities for the defects to appear. Ion irradiation also gives rise to the sputtering of Se atoms, that is, the formation of Se vacancies (V$_{\text{Se}}$), but these events were not so common.

According to the DFT MD simulations, the most probable defects that appear upon 25 eV Cr-ion irradiation are Cr adatoms, Cr@Mo, and X-sub defects. The Cr atoms that pass through the MoSe$_2$ sheet will likely form adatoms attached to the bottom of MoSe$_2$. Self-annealing of defects at finite temperatures at which irradiation was carried out in the experiment can affect their concentrations in the implanted samples. To get insight into the possible evolution of defects, we assessed the defect formation energies $E_f$ as done previously. For adatoms, interstitials, and X-sub defects, $E_f$ was calculated as the energy difference between the system with the Cr atom and the pristine system plus isolated Cr atom. For the Cr@Mo, Cr@Se, and V$_{\text{Se}}$ configurations, the energies of isolated Mo and Se atoms were also taken as a reference. We note that the listed defect formation energies for the Cr@Mo, Cr@Se, and V$_{\text{Se}}$ configurations, the energies of isolated Mo and Se atoms were also taken as a reference. We note that the listed defect formation energies for the Cr@Mo, Cr@Se, and V$_{\text{Se}}$ cannot be used to assess the equilibrium concentrations of these defects, as the chemical potentials were chosen to match isolated, that is, sputtered, atoms. This can be done, though, if the chemical potentials of the displaced Se and Mo atoms are chosen in such a way that they reflect the actual experimental conditions that the potential can be anywhere between the values corresponding to the Se- or Mo-rich limits. This would result in lower formation energies, as the sputtered atoms would be incorporated into the lattice. It can also be assumed that the displaced Se atoms form Se clusters at the surface, which would give rise to the lowering of Cr@Se defect energies.

As evident from Table 1, $E_f$ for adatoms is lower than for the interstitials, so that at finite temperatures, the interstitials will most likely be “pushed away” from the Mo plane and form adatoms. We note that this result was obtained for a relatively small 90-atom supercell, and in the larger system, the difference between these energies is smaller, as reported earlier. Nevertheless, even for equal formation energies at zero temperature, with an account for the entropic term in the Gibbs energy, the probabilities for the adatoms should be higher due to a larger configurational space. Some X-sub defects may also be converted to Cr@Se configurations, especially in the Mo-rich limit, when Se vacancies are present, but the energetics of this process naturally depends on the experimental conditions, that is, the choice of Se chemical potential. The Cr@Se defects can also appear due to the adsorption of Cr atoms on Se vacancies, as this is energetically favorable due to the saturation of dangling bonds. Thus, one can expect that the most prolific defects in the samples are Cr adatoms (or Cr clusters on top of MoSe$_2$), X-sub, as well as Cr@Mo and Cr@Se substitutional configurations.

2.4. DFT Calculations of Optical Properties. To investigate if Cr defects introduce states in the band gap of the MoSe$_2$ ML that are optically active, we have simulated optical absorption spectra for MoSe$_2$ with Cr defects in various positions. The simulations are based on a $5 \times 5$ supercell. Each supercell hosts one Cr defect. The unfolded band structures are shown in the Supporting Figure S5. All defects give rise to states in the band gap. The absorption spectrum $\text{Im}[\epsilon(\omega)]$ with the energy-dependent macroscopic dielectric function $\epsilon(\omega)$ has been calculated within the random-phase approximation in the limit $\hbar \omega \rightarrow 0$. Optical matrix elements and local-field effects are taken into account. It should be pointed out that self-energy corrections (such as GW) or electron–hole interactions (as described by the Bethe–Salpeter equation) are neglected. Self-energy corrections and electron–hole interactions are known to have a partially compensating effect on

![Figure 6. First-principles MD simulation of the ion implantation process into ML MoSe$_2$. (a) The setup for simulations of ion impacts. (b) Impact sites used in the simulation. (c) Atomic structures of the defects likely to appear impacts of energetic Cr ions.](image-url)
the band gap, while the former tends to increase the band gap, the electron–hole interactions make the optical band gap smaller. Due to this compensating effect, the present theoretical results can be seen as approximate spectra specifically showing the impact of the defects. However, quantitative differences between theory and experiment should be expected due to the neglect of many-body effects and also due to the difference in the dielectric environment. The theoretical spectra are shown in Figure 7. Absorption below the band gap (around 1.6 eV) is present for all defects and originates from transitions involving the defect states.

There is an optical transition for X-sub at 1.5 eV, which is in the same energy range of the D emission from the PL spectra between the valence band and an acceptor state of X-sub. This state results from the coupling of the conduction band at the K-point with the Cr defect state. The energy of this transition is similar to that of the MoSe$_2$ ML with a vacancy.55–58

The weak transition involving a deep acceptor state at 0.9 eV is outside the spectral range of our experiments. We note that the coupling between the conduction band and the defect state shifts the conduction band minimum from K toward the Γ point (Supporting Figure S5). However, the resulting suppression of PL would not be visible in the experiment due to the low density of defects and only the local opening of the band gap.

Well-defined spin-degenerate acceptor levels are also introduced by Cr substituting the Mo atom in the lattice (Cr@Mo). Optical transitions from this defect state into the valence band states can be seen in Figure 7 in the range between 1.4 and 1.5 eV, which is also in a similar energy range to the D peak PL emission. The band-to-band transition is shifted to higher energy compared to the pristine MoSe$_2$ ML because of the coupling between the conduction band and the defect state. However, similar to the X-sub configuration discussed above, it is unlikely to observe this blueshift in the PL spectra due to the low defect density.

The coupling of the defect and conduction band results in a gradual increase of the above-band-gap absorption for Cr substitution into the Se site (Cr@Se). This defect type also introduces a donor state at the Fermi level and two single-spin, deep defect levels. The signal from the donor state merges with the band-to-band absorption. Otherwise, the Cr defect at the Se site hardly affects the MoSe$_2$ band structure. Several weak optical transitions are present at a large range of energies (down to 500 meV below the band gap).

Interstitial Cr introduces several deep defect levels in the band gap, and again the highest state couples to the conduction band shifting the conduction band minimum to the A point. The absorption spectrum does not contain discrete absorption lines but a gradually increasing absorption from 1.2 eV.

### 3. DISCUSSION

Radiative recombination of an electron (e$^-$) bound to a defect state with the valence band hole (h$^+$) can explain the measured PL. Considering that our DFT calculations do not show donor states at high enough energy, the electron here is likely to occupy an acceptor. In this scenario, an exciton bound to a negatively charged acceptor (A$^-$X) dissociates into A$^+$h$^+$ and a free electron in the conduction band. Following radiative recombination, A$^+$h$^+$ becomes neutral acceptor A$^0$. Theoretical modeling of A$^-$X indicated a binding energy of only a few meV compared with the A$^0 + e^-$ state, which is of the same order of magnitude as the activation energy of the D line determined from the Arrhenius plot. Among the potential defects identified by MD calculations, Cr@Mo, X-sub, and Cr@Se have nonzero matrix elements for optical transitions between acceptor states and valence band. Other configurations, e.g., interstitial Cr or Se vacancies, are unlikely to be present. Besides, neither would explain the data (see Figure 7 and Supporting Information Note 4).

The measured 1/e recombination time is longer than the lifetimes reported for band-to-band and localized state recombination in MoSe$_2$. Low oscillator strength of the transition can result from the spatial separation of electrons and holes, as for Cr@Se or X-sub. However, since this lifetime is longer than that of the spin dark states in WSe$_2$, which is only a few nanoseconds, this transition could also be from a spin-forbidden state. Such a state would correspond to the charge configuration of A$^0$ for the Cr@Se defect in the absence of exchange interactions between electrons in the conduction band.

The g-factor of the D emission is negative but much smaller than those for X or X'. With large g-factors for electrons in the valence band, it implies either a large g-factor for an electron on the acceptor level near the conduction band (e.g., in Cr@Mo or X-sub configuration) and valley-selective transitions or reduced g-factor of holes in the valence band. The latter could be caused by the hybridization of the valence band with the defect level as in the Cr@Se configuration. Further insight would require higher magnetic field measurements and theoretical input.

### 4. CONCLUSIONS

In conclusion, we demonstrated the ultra-low-energy ion implantation of Cr ions (at 25 eV) into a MoSe$_2$ ML. The implantation was performed with ions at 25 eV and an ion fluence of $3 \times 10^{17}$ cm$^{-2}$; the resulting material retains high optical quality as evidenced by clear excitonic PL. Implanted Cr ions introduce an additional low-energy PL signal at around 1.51 eV visible at the onset of n-doping. Molecular dynamics calculations identified defects that can be generated by implantation. We found that Cr atoms can substitute for...
both Mo and Se atoms. In the latter case, the Cr atom is slightly more likely to bind an additional Se atom than not. The defects’ stability, including interstitial Cr, depends on the post-implantation treatment and the final configuration of Se and Mo, which are not in the lattice. DFT calculations revealed that all of the probable defects introduce one or more defect states in the MoSe₂ band gap with nonzero matrix elements for optical transitions. It is impossible to identify with certainty which defect is the origin of the D line, Cr at the Se site with the Se adatom (X-sub), and perhaps Cr at Mo (Cr@Mo) seems to fit best with the measured data. Further experiments, for example, the implantation of Cr only into the Se sublattice or implantation through the hBN protective layer to avoid environmental changes, could be considered to distinguish between the cases.

More generally, this study shows that implantation of heavier elements into the metal sublattice of TMD MLs is possible without the visible loss of material quality as evidenced by the unchanged excitonic PL of gated MoSe₂. However, the implantation process is complex, and simulations of the possible outcomes are necessary to identify material systems of the desired properties. In the search for single photon emitting sites, it is also worth noting that upon implantation with a very low fluence, it should be possible to address individual Cr atoms at different lattice sites. Implantation of foreign atoms might be used to introduce catalytic sites in 2D materials or to add functionalization such as magnetism.

5. METHODS

5.1. Atomistic Simulation. We used DFT MD as implemented in the VASP code. The Perdew–Burke–Ernzerhof (PBE) exchange and correlation functional was employed. The evolution of the system was modeled using the microcanonical ensemble. A cutoff value of 300 eV was chosen for DFT MD, and sampling over the Brillouin zone was done using a 3 × 3 × 3 k-point mesh. The time step was chosen to be 0.1 fs, which provided energy conservation better than 0.1 eV.

5.2. Band Structure and Absorption Spectral Calculation. Density functional theory (DFT) simulations were performed in supercells of 5 × 5 primitive unit cell each. This was constructed with lattice constants of a = 3.28 Å and c = 12.918 Å of the hexagonal lattice. An internal structure parameter of z = 0.125 was used. The defect systems were spatially relaxed using FLEUR until the residual atomic forces had fallen below 5 × 10⁻² eV/Å. The subsequent calculation of the macroscopic dielectric function in SPEX and includes local-field effects. Calculations of 2D materials with 3D periodic boundary conditions are computationally expensive because the decoupling of neighboring layers in the z direction requires large supercells in this direction. In the case of 2D systems with defects, the computational cost grows considerably, particularly in the case of low defect concentrations, because suppressing the unwanted defect–defect coupling requires large supercells in the x and y directions. To facilitate the calculations of the dielectric function, we had to reduce the reciprocal cutoff radius from 4.1 to 3.6 Bohr⁻¹ in the case of the X-sub defect system. However, this should not affect the form of the respective spectrum shown in Figure 7.

The band structures presented in the Supporting Information are made up of 320 k points along the unfolded high-symmetry path Γ–M–K–Γ. Here, “unfolded” means that the high-symmetry points refer to those of the defect-free MoSe₂ ML. The necessary unfolding of the band structures of the defect systems has been carried out with a new implementation in the FLEUR code, adapting the technique described in ref 69 to the LAPW basis. In this technique, a spectral weight is assigned to each state plotted in the band structure. The weight wₙ(k) for the n-th state at k of the unfolded path is given by

\[ wₙ(k) = \sum_{G} C_{nG}^{*}(G) C_{nG}(G') S_{GG'}(k') \]

where \( k' = k + G' \) with a suitable reciprocal lattice vector \( G' \) that folds \( k \) back into the (smaller) Brillouin zone of the defect system. The \( G' \) sum runs over the set of all reciprocal lattice vectors (of the defect system) at \( k' \), and the \( G \) sum runs over the set of reciprocal lattice vectors (of the pristine system) at \( k \). The latter is a subset of the former. The wave functions are represented in the LAPW basis \( \chi_{nG}(k) \) with coefficients \( C_{nG}(G) \) and overlap matrix \( S_{GG'}(k) = \langle \chi_{nG}(k') | \chi_{nG'}(k) \rangle \). A detailed description of the source and the implementation can be found in the references.

5.3. Sample Preparation. Si with 90 nm thick dry-thermally grown SiO₂ chips with 60 nm thick Ti/Au contacts (pre-patterned by electron beam lithography) were used as the substrate. Before sputter transfer, the chips were cleaned in acetone and isopropanol (IPA) under bath sonication, blown dry with N₂ and treated with oxygen plasma (300 W, 200 sccm for 10 min). Few-layer graphite, MoSe₂ (from 2Dsemiconductors) MLs, and hBN (from Takashi Taniguchi and Kenji Watanabe) multilayers were mechanically exfoliated from bulk crystal using polydimethylsiloxane (PDMS) stamps (Gel-pak DGL X4 films) and transferred onto the substrate using the dry viscoelastic transfer process. The process was performed in a N₂-filled glovebox. After transferring the graphite (5.5 nm thick) and bottom-hBN (20 nm thick) flakes, the sample was annealed in a H₂/Ar (1:10 ratio) atmosphere at 300 °C for 3 h to improve the top surface for the subsequent MoSe₂ ML transfer. After transferring the top-hBN (15 nm thick), the sample was annealed in low vacuum (5 × 10⁻³ mbar) at 150 °C for 2.5 h to improve interfaces in the vdW stack. Electrical contacts, provided by the Ti/Au lines, were made to the MoSe₂ flake and the graphite backgate. After each transfer, the heterostructure surface was checked with atomic force microscopy to ensure a sufficiently flat area in the stack and to obtain the flakes’ thickness. MoSe₂ ML’s quality was confirmed by Raman and PL spectroscopies at room temperature.

5.4. Ion Implantation. Bronze tips were used to fix the sample on a holder, making contact with the sample’s Au pads and, thus, the ML. To remove volatile contamination from the sample, the sample chamber was then evacuated to 10⁻⁹ mbar for several hours. The sample was heated to 150 °C for 10 min to remove residual volatile adsorbrates and then to 220 °C during the implantation. A foil was used as a feedstock to provide 55Cr ions. After extraction, the ions are decelerated from 30 keV to 25 eV directly in front of the sample. Since the deceleration voltage is set relative to the potential of the source anode, this energy represents the upper limit, with a tail toward lower energies. The fluence of the ions was set to 3 × 10¹⁵ cm⁻². The fluence was verified by test implantations using the Rutherford backscatter spectrometry (more information in the Supporting Information Note 1). A detailed description of the source and the implantation system can be found in the references.

5.5. Optical Measurements. PL spectroscopy was performed at 10 K (unless otherwise specified) in a He-cooled cold-finger cryostat (Cryoindustries) with a heating element (allowing a sample temperature range from 10 to 300 K). For PL measurements, the laser beam—688 nm (1.80 eV) from a Ti:Sa laser—is passed through a 680 ± 5 nm band-pass filter before being focused by an aspheric lens (NA = 0.47) into a spot of 1.6 μm in diameter on the sample. Unless otherwise specified, the laser power on the sample was at 1 μW for PL experiments. The PL signal is collected by the same lens and passed through a 700 nm low-pass filter before being focused by an achromatic doublet (NA = 0.24) through the entrance slit of a Czerny–Turner spectrometer, dispersed by a 600 l/mm grating onto a CCD camera. For gate dependence and temperature dependence PL, the laser power was kept at 1 μW. For PLE, the excitation power ranged from 2 to 5 μW, and the PL intensity is normalized to the power density for final data.

For time-resolved PL, the excitation was done using a pulsed laser at 660 nm (1.88 eV) with a 200 ps pulse length, a 2.5 MHz repetition rate.
rate, and a 2.8 μW average power. The PL signal is directed through an 800 nm (1.55 eV) low-pass filter on the detection path before entering an avalanche photodiode with a 30 ps time resolution. The histogram of the time difference between the laser pulses and PL emission was acquired with a time tagger.

The sample was mounted on an x-y-z Attocube stage in a He flow cryostat (attoDRY2100) for magneto-optics measurement at temperature T = 1.8 K. A magnetic field up to ±8 T was applied perpendicularly to the sample (Faraday configuration). The excitation laser beam (688 nm, i.e., 1.80 eV at 4 K) was passed through a combination of a linear polarizer set to pass the same objective. It was passed through a combination of a 700 nm band edge filter (with a 680 nm band-pass filter and a linear polarizer in a H-configuration. The laser was focused by an aspheric lens (NA = 0.47) into a spot of ±1.6 μm in diameter on the sample. The emitted PL was collected with the same objective. It was passed through a combination of 1/4, 1/2 waveplates, and a linear polarizer set to pass the σ± polarized light. It was then propagated via a single-mode optical fiber toward the entrance slit of a Czerny–Turner spectrometer, where it was dispersed by a 600 l/mm grating onto a CCD camera. A long-pass filter (with a 700 nm band edge) was inserted between the fiber output and the spectrometer entrance to remove any remaining laser light.

### ASSOCIATED CONTENT

**Data Availability Statement**

The data supporting the findings of this study are available within the paper and its Supporting Information files. Data are also available from the corresponding author upon reasonable request.

**Supporting Information**

The Supporting Information is available free of charge at https://pubs.acs.org/doi/10.1021/acsami.3c05366.

Additional experimental details on the RBS measurement of Cr implantation on the test ta-C substrate; spatial PL maps of D, X, and X’; polarization-resolved PL; Raman and PL spectroscopic studies of vacancies in MoSe2 ML; MD simulation and TEM studies of Cr implantation on MoS2 ML; unfolded band structure of Cr-implanted MoSe2 ML with various defect configurations; and charge carrier density conversion from gate voltage (PDF)

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**Author Contributions**

B.E.K., H.C.H., and M.N.B. conceived and designed the experiments. S.K. and A.V.K. performed MD simulations. S.R., C.F., and S.B. performed DFT calculations for band structures and absorption spectra. T.T. and K.W. grew high-quality hBN crystals. L.Z. processed the Si/SiO2 substrate with patterned markers and metal contacts. M.N.B. prepared the samples on the Si/SiO2 substrate. M.A. and H.C.H. performed ion implantation. M.N.B. and L.Z. acquired and analyzed PL and Raman data. All authors discussed the results and contributed to the writing of this manuscript.

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**Notes**

The authors declare no competing financial interest. All scripts used to generate the results in this study are available from the corresponding author upon reasonable request.

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REFERENCES


Supporting Information for
Optical properties of MoSe₂ monolayer implanted with ultra-low energy Cr ions

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Rutherford backscattering spectrometry (RBS) studies were carried out to verify the nominal implantation fluence of our experiments. An 860 keV helium ion beam was generated using a Cockcroft-Walton accelerator and then directed onto the sample surface. The backscattered ions were detected by a silicon charged-particle radiation detector under an angle of 165° to the ion beam direction. The semiconductor detector has an active area of 25 mm² and is located at a distance of 88 mm. Figure S1 shows an RBS spectrum for Cr implantation at 25 eV with a fluence of $3 \times 10^{15}$ cm⁻² on a Si/ta-C substrate. Fitting procedure using SIMNRA [1] gives Cr density of $3.03 \pm 0.13 \times 10^{15}$ cm⁻², which agrees well with the given values in the Methods section. The test implantations are performed with a fluence of $3 \times 10^{15}$ cm⁻² to achieve a high count rate in RBS in a reasonable acquisition time and to perform a better fit in SIMNRA.

Figure S1: RBS spectrum for Se implanted in ta-C on a Si substrate. The implantation was performed at 25 eV with a fluence of $3 \times 10^{15}$ cm⁻². Fit curve was done using SIMNRA.
Supplementary note 2 - Spatial distribution of D peak

Figure S2 shows the 2D integrated micro-PL (µ-PL) maps for D, X and X− emissions. Compared to the excitonic emission map of X and X−, D emission is observed only in the implanted MoSe₂ ML area and does not come from the hBN or Gr layer underneath. The emission is also not from localised sites, e.g. wrinkles, scratches or bubbles in the ML, but rather the whole ML. The apparent difference between the bright and dark halves in the ML is likely from inhomogeneous doping provided by the bottom Gr gate.

Figure S2: µPL maps of Cr-implanted MoSe₂ ML. The PL intensity was integrated around (a) D, (b) X, and (c) X− emission. The integrated PL signal is summed over the energy range indicated in the shaded region in respective single spectra in (d), (e), and (f).
Supplementary note 3 - Polarization resolved PL

A linear polariser, a $\lambda/2$-waveplate and a $\lambda/4$-waveplate were inserted in the excitation path (before the beamsplitter) to set the polarisation state of the laser beam from a diode laser (655 nm in wavelength and 4.59 $\mu$W in power on the sample). On the detection path, a $\lambda/4$-waveplate, a $\lambda/2$-waveplate and a linear polariser were placed to set the detected polarisation state. D line shares polarisation properties with the X and X$^-$ as shown in figure S3. Excitation with circularly polarised light resulted in a low degree of circular dichroism for X and X$^-$ emissions, typical for MoSe$_2$ [2–4]. The degree of dichroism, defined as $P_C = (I_+ - I_-)/(I_+ + I_-)$ where $I_\pm$ are PL intensity detected in $\sigma_\pm$ states, is similar for D compared with X and X$^-$. 

Figure S3: Polarization-dependent PL of Cr-implanted MoSe$_2$ at 10 K. The sample is excited with left ($\sigma^+$) circularly polarised light, and PL is detected in left - red curve - and right ($\sigma^-$) - dotted black curve - states. D, X$^-$ and X exhibit low circular dichroism $P_C$ at below 0.05.
According to MD simulation (table 1 in main text), we should exclude the Se vacancy as the signal’s origin. Vacancy introduces a donor state at the Fermi level hybridised with the valence band and an acceptor state deep in the bandgap [5–8]. An optical transition between the defect levels is not allowed (figure 7). The lowest allowed energy optical transition is between the valence band state at the Γ point and the deep acceptor level. The existing literature reports that vacancies form non-radiative recombination sites that quench PL [9, 10] or that they contribute to sub-bandgap PL but only at low temperature [11–13], which is in contrast with our data (see RT PL from our samples in figure S4b). In addition, the energy shift of the D line with the temperature [14] (figure 4c) is weaker than that of X, unlike the fast change reported for vacancies in MoSe$_2$ [11]. At sufficient density (around 8%), vacancies can blueshift the PL and downshift the Raman lines [7]. In contrast, we did not see such changes in our Cr-implanted MoSe$_2$ ML (figure S4).

Figure S4: Optical spectroscopy of defected MoSe$_2$ ML. Room temperature Raman (a,c,e) and PL (b,d,f) spectra of Cr-implanted MoSe$_2$ ML (a,b), annealed ML (c,d) and Kr-implanted MLs (e,f), with a pristine ML’s spectrum for comparison. Raman spectra are all normalised to Si signal at 520.5 cm$^{-1}$.

To ensure that one can exclude the role of vacancies in the D emission, room temperature Raman and PL spectra...
of MoSe$_2$ MLs with vacancies were compared to Cr-implanted MoSe$_2$. To create vacancies, one sample of MoSe$_2$ was annealed at 300 °C in low vacuum ($5 \times 10^{-2}$ mbar) for 2.5 hours [13]. Another two samples were implanted with Kr$^+$, which, together with other noble gases, is commonly used for creating vacancies and their complexes in 2D materials [12, 13, 15–22]. Ion implantation was done at 25 eV energy for introducing vacancies [23, 24], with fluences of $3 \times 10^{11}$ and $3 \times 10^{12}$ cm$^{-2}$ at elevated temperature of 220 °C, after being pre-annealed for 30 minutes at the same temperature in the implant chamber to remove volatile adsorbates. The higher fluence corresponds to the same Cr fluence in the main text. The lower fluence is about 10 times higher than the upper limit of potential vacancies density predicted for the Cr implanted sample by the atomistic MD simulation in the main text.

Figure S4 shows the room temperature Raman and PL spectra of MoSe$_2$ MLs before and after Cr implantation, annealing and Kr implantation (as already described above or in the main text). Since slight variations in PL and Raman spectra are possible from sample to sample, the spectra from the same ML before and after processing are shown. Cr-implantation introduces a small upshift in the out-of-plane Raman vibrational mode $A'$ (figure S4a). The upshift is expected for Cr atoms in the lattice because it stiffens the lattice bonds and increases the restoring force and the $A'$ frequency. Annealing and Kr implantation downshift this Raman line (figures S4c and S4e). Such a downshift has been reported before for MoSe$_2$ MLs with vacancies [7, 25–27]. It was explained by the lattice bond loosening and lowering the restoring force. PL emission of the Cr-implanted ML is 15 meV redshifted compared with the pristine ML. It also shows an emission band around 120 meV below the free exciton line (figure S4b). This low-energy emission is also observed at low temperatures. On the other hand, the annealed ML has a very slight blueshift (figure S4d), consistent with several other reports [7, 25]. Kr-implanted MLs’ PL is heavily quenched (figure S4f). Some signal is visible only when the excitation laser power is raised 15000 times (from 17 nW to 261 µW). The disagreement from these experiments doesn’t favour vacancies being the origin of the D emission from the Cr-implanted ML.

Raman and PL spectra presented in this section were acquired under ambient conditions (room temperature and pressure) using a confocal Raman microscope (Renishaw inVia) with 532 nm excitation laser (Coherent Compass 315M 150SL). The laser power was set between 0.017 and 261 µW for sufficient signal intensity while preventing the sample from heating during exposure. An objective lens (50×, NA = 0.75, Leica N-plan EPI) collected the Raman signal, which was then dispersed by a 2400 l/mm grating on the CCD camera, giving a spectral resolution of 1 cm$^{-1}$. PL signal was dispersed with a 600 l/mm grating, yielding a resolution of 0.147 nm.
Supplementary note 5 - MD simulation and TEM studies of Cr implantation in MoS\textsubscript{2}

To compare the types of defects obtained in the simulations to the available experimental data, we also modelled ion implantation into ML MoS\textsubscript{2}. The results are presented in supplementary table S1. We note that interstitials cannot exist in ML MoS\textsubscript{2} due to a smaller unit cell size than that of MoSe\textsubscript{2}. Configurations predicted by the simulation were observed in the atomic-resolution TEM characterisation of ML MoS\textsubscript{2} implanted with Cr under similar conditions [28]. It was noted that the relative abundance of defects, determined by the intensity-based atomic site assignment, was heavily affected by the presence of carbon contamination on the ML surface. In addition to the poor resolution in the experimental images, this renders accurate quantification of the elements difficult.

**Table S1: Results of DFT MD simulations of 25 eV Cr ion irradiation on single layer MoS\textsubscript{2}.** The probabilities \( p \) of likely defect configurations to appear along with the formation energies \( E_f \) of these configurations are listed.

<table>
<thead>
<tr>
<th>Configuration</th>
<th>( p )</th>
<th>( E_f ) [eV]</th>
</tr>
</thead>
<tbody>
<tr>
<td>adatom</td>
<td>0.12</td>
<td>-0.98</td>
</tr>
<tr>
<td>X-sub</td>
<td>0.12</td>
<td>-0.74</td>
</tr>
<tr>
<td>interstitial</td>
<td>0.00</td>
<td>0.93</td>
</tr>
<tr>
<td>Cr@Mo</td>
<td>0.41</td>
<td>3.06</td>
</tr>
<tr>
<td>Cr@S</td>
<td>0.12</td>
<td>2.87</td>
</tr>
<tr>
<td>VS</td>
<td>0.13</td>
<td>6.53</td>
</tr>
<tr>
<td>passed through</td>
<td>0.10</td>
<td>0.00</td>
</tr>
</tbody>
</table>
Supplementary note 6 - Unfolded band structures including implanted defects

The main text shows the dielectric functions of MoSe$_2$ MLs containing several Cr-implantation introduced defects. In the following, their unfolded band structures are shown, which means that the band structures are shown in the first Brillouin zone of the pristine unit cell to visualise better the perturbation that the defect introduces. The methodology is briefly recapitulated in the method section of the main text.

Single atomic defects should show up as flat energy levels if the computational supercell is large enough for the periodic images of the defect atom not to interact. It is not always the case here due to the computational resources that such large supercell would require. Wherever a defect state crosses and interacts with a band of the host lattice, a hybridisation of the bands is visible.

Figure S5: DFT calculation for unfolded band structure of Cr-implanted MoSe$_2$ ML with different Cr defect configurations: (a) Cr@Mo, (b) Cr@Se, (c) interstitial Cr atom, (d) X-sub. Calculations were performed in 5×5 supercells (with a reciprocal cutoff radius of 4.1 Bohr$^{-1}$ for (d), and 3.6 Bohr$^{-1}$ for its respective absorption spectrum in the main text) [5]. The calculations include two spins, shown here in red and blue, without spin-orbit coupling. Defects (and bands) in (a) and (d) are spin degenerate. Defect-induced states in (b) and (c) can be occupied by one electron. The influence of the implanted defect is visible via the defect-induced states inside the bandgap. A thick symbol size (high unfolding weight) means that the symmetry of this state corresponds to the one of the primitive cell (pristine material).
Supplementary note 7 - Charge carrier density conversion from gate voltage

The carrier concentration \( n \) is estimated by the simple parallel plate capacitor model \([29, 30]\). The bottom hBN flake acts as a dielectric of the capacitor with dielectric constant \( \epsilon_{\text{hBN}} \approx 3.4 \) \([30–32]\). Upon applying gate voltage \( V_g \), we have

\[
C = \frac{Q}{(V_g - V_0)} = \epsilon_{\text{hBN}} \epsilon_0 \frac{A}{t}
\]

with \( C \) the capacitance of the graphite/hBN/MoSe\(_2\) stack, \( Q \) the charge on MoSe\(_2\) ML at \( V_g \), \( V_0 \) being the gate voltage at charge neutrality point (taken to be at minimum trions PL intensity), \( \epsilon_0 \) the vacuum permittivity, \( A \) the hBN flake’s area, and the flake’s thickness \( t = 20 \text{ nm} \). Rearranging the above equation gives the charge carrier density \( n \) on the ML

\[
n = \frac{Q}{eA} = \epsilon_{\text{hBN}} \epsilon_0 \frac{(V_g - V_0)}{et}
\]

where \( e = -1.602 \times 10^{-19} \text{ C} \) is the electron charge.


